



EC
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Norio KIMURA et al.

Serial No. 09/777,707

Filed February 7, 2001

POLISHING APPARATUS

Confirmation No. 4320

Docket No. 2001_0122A

Group Art Unit 3723

Examiner Willie W. Berry, Jr.

AMENDMENT

Assistant Commissioner for Patents,
Washington, D.C.

Sir:

In Response to the Office Action dated December 7, 2001, please amend the above-identified application as follows:

In The Specification:

Please amend the specification as follows.

Please replace the paragraph beginning at page 4, line 21, with the following rewritten paragraph.

By preliminarily supplying a pressurized fluid to the above-mentioned cylinder so as to counter the weight of the dresser, the pressure between the dresser tool and the polishing surface of the turntable can be easily minimized to a level less than the weight of the dresser and adjusted to an arbitrary value exceeding that level (for example, a value in a range of 10 N to 300 N).

Please replace the paragraph beginning at page 7, line 21, with the following rewritten paragraph.

The air cylinder 9 is a low-friction type and the kinetic frictional resistance generated when a piston in the air cylinder 9 is moved is about 0.44 kg or less. Air is supplied through the controller

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